

# Enabling Advanced Chiplet and SiP Architectures: Materials, Interconnects, and Thermal Solutions.

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Speaker:

Martin Metzler, Director Technical Business Development Europe



**Martin Metzler**



Director, Technical Business Development  
MacDermid Alpha Electronic Solutions



**My journey through the  
KEYNOTE presentation  
and the preparation**



The finalization of the pictures took 10 runs, with several adaptations on my and the background.

Standard GPU: NVIDIA A100; GPU-time: 30-60sec; Compute-capacity: 3-12PFLOP\*s; Energy: ~2Wh

Evolution in the data center sector:

V100 (Volta) = 0,4   A100 (Ampere) = baseline   H100 (Hopper) = 3x   H200 (Hopper+) = 4x

**2017**

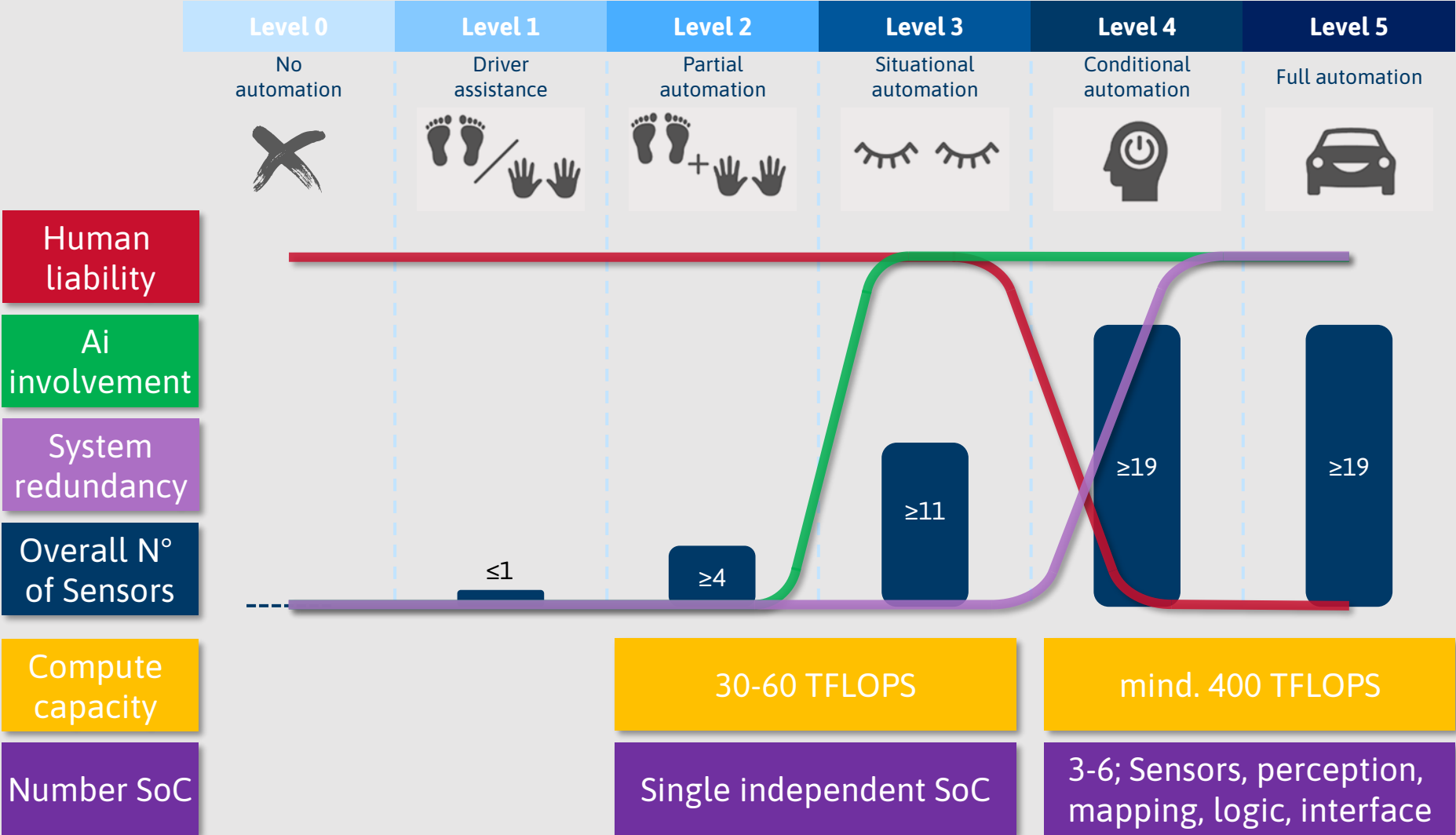
**2020**

**2022**

**2024**

# Market Trend in Autonomous Driving

ADAS Levels (SAE J3016), Source: IDTechEX; Cloud factory and market assumption



System Scalings  
Hotspot Management  
Thermal Resistance ( $R_{th}$ )  
Thermocompression Bonding (TCB)  
Chiplet Architecture  
Coplanarity  
Through-Silicon Via (TSV)  
Thermal Interface Material (TiM)  
Design-Technology Co-Optimization (DTCO)  
Moore's Law  
Micro-Bump

Strain  
Die Attach  
Die Crack  
CTE

Nano-Silver Sintering  
Copper Pillar

Modulus  
Advanced Packaging  
Interposer Materials  
Interconnect Reliability  
System-in-Package (SiP)  
Hybrid Bonding  
Redistribution Layer (RDL)  
Lifetime Modeling  
Sustainability

# Advanced Packaging:

- **2.5D Integration** of Dies
  - Side-by-side integration of multiple Dies
  - High-Density interconnects, Micro-Bumps
  - Silicon, Organic or Glas interposer
  - Through-Silicone-Vias (TSV) on Silicon Interposer
  - EMIB, Embedded Multi-Die Interconnect Bridge (Intel)
- **3D Integration** of Dies
  - Vertical integration, stacking of multiple Dies
  - TSV Stacking with hybrid bonding
- **Fan-Out Packaging** like FO-WLP or FO-PLP
  - Redistribution Layers (RDL) without a classical substrate
- **System-in-Packages (SiP)** as functional, final system
  - Combination of Dies, passive Components, MEMS and Sensors
- **Embedded** Die and Substrate integration
- **Hybrid Packages** as combination of 2.5D + 3D + SiP

# Drivers for Advanced Packaging:

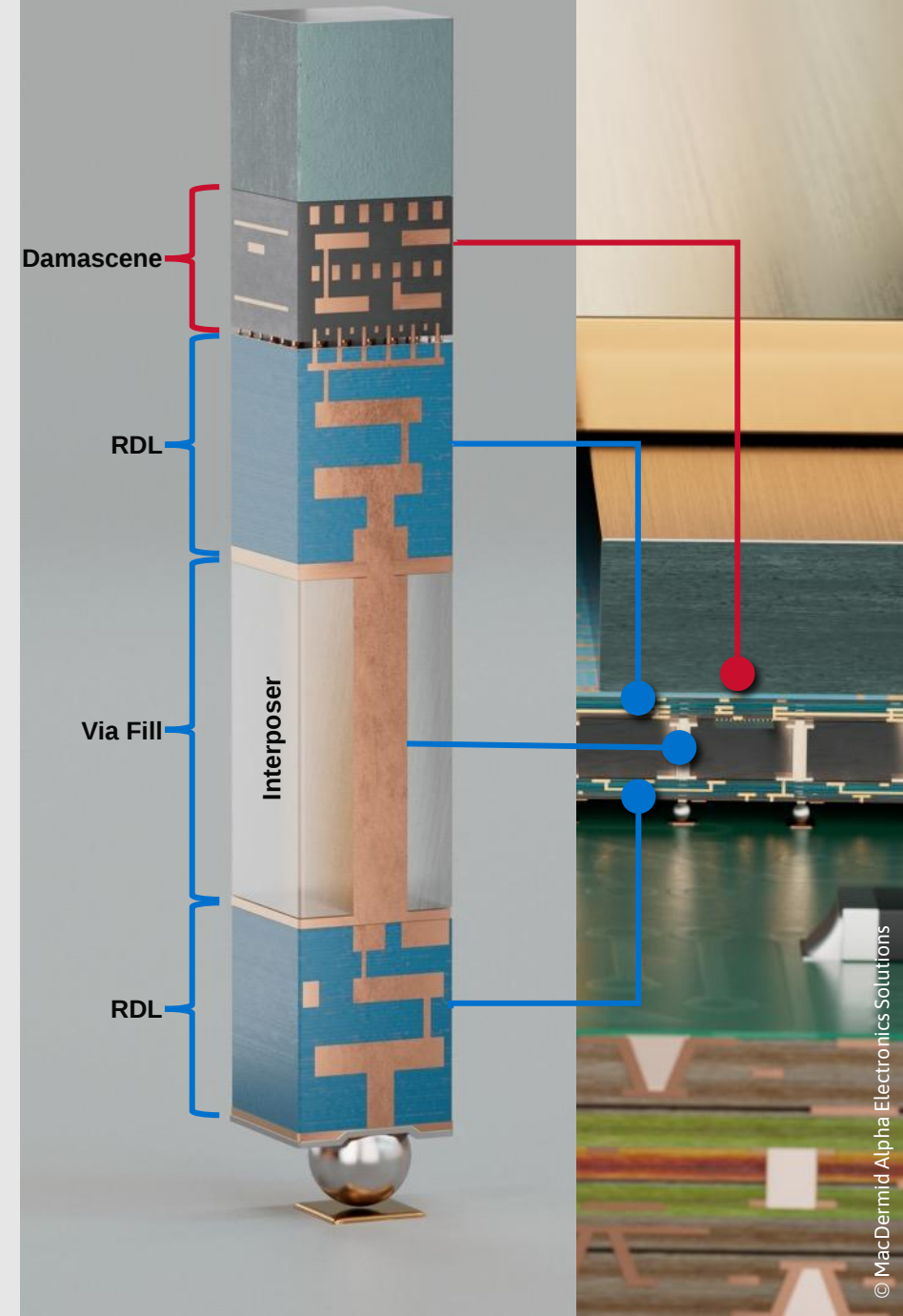
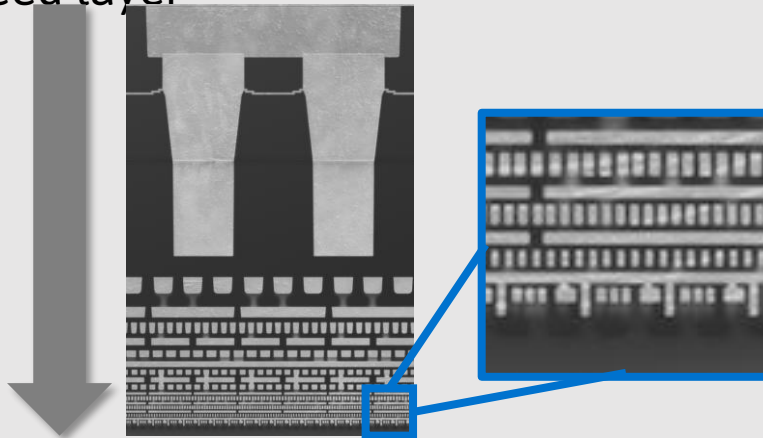
- **Cost Efficiency**
  - Higher yield in Die production
  - Multiple usage of Chiplets
- **Higher Performance**
  - Shorter signal paths
  - Higher signal integrity
  - Lower latency
- **Higher Energy Density and Efficiency**
- **Improved Thermal management**, high power/ energy densities can be controlled
- **Application-Specific** use of customized and **optimized Technology** (heterogeneous integration)

# Interconnect Technologies

## Damascene

- **Where is it used?** On-Chip-Level, IC Production
- **Challenge and Development:**
  - **Source Yole Group**, logic nodes below 5 nm are projected to account for over 20% of global wafer volume by 2027, with 2 nm entering full-scale production in 2025–2026
  - PVD-Processes struggle to achieve a uniform coverage of seed layers
  - New Chemistry Development are using a new alkaline system which enables electrochemical plating of such challenging structure without a seed layer

**The Road to Finer Pitches**  
**From 130nm to 2nm**



# Interconnect Technologies

## Hybrid Bonding

- **Principal**, Atomic diffusion between Cu-to-Cu Oxide
- **Benefits:**
  - **Pitch** <10 $\mu\text{m}$ , enabling up to 1 Million connections per  $\text{mm}^2$
  - **Low Resistance, High Reliability, High Energy Efficiency**
  - **No Induction-Effect**, HF and High-Switching-Speed
- **Used in:**
  - 3D Stacking for Die-to-Die or Wafer-to-Wafer
  - Chiplet Integration on High Density Die-to-Die
- **Challenges:**
  - Package alignment in Nano-Meter-Range
  - Grain structure of copper  $\rightarrow$  Target fine grains, <0,2 $\mu\text{m}$  for processing

As-plated FG-Cu



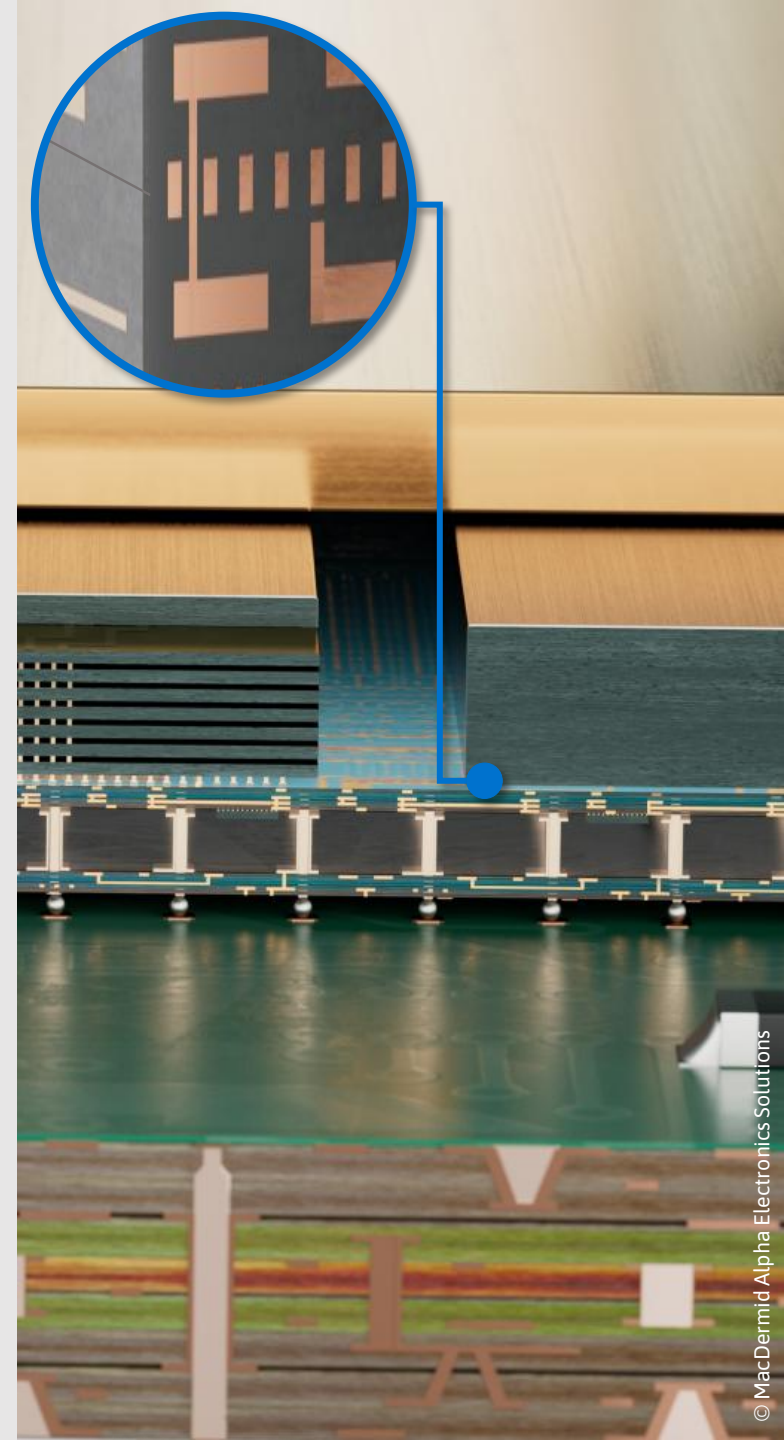
After Pre-bonding annealing



After Bonding annealing



— 1  $\mu\text{m}$

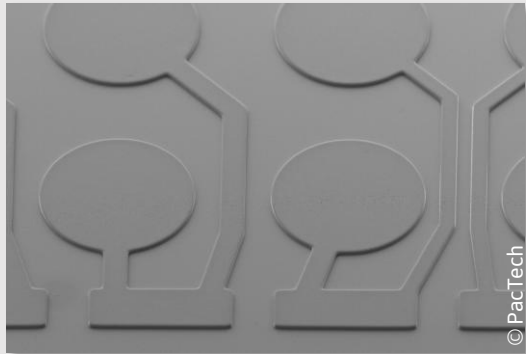


# Interconnect Technologies

## Random-Distribution-Layer (RDL) and Via-Filling Materials

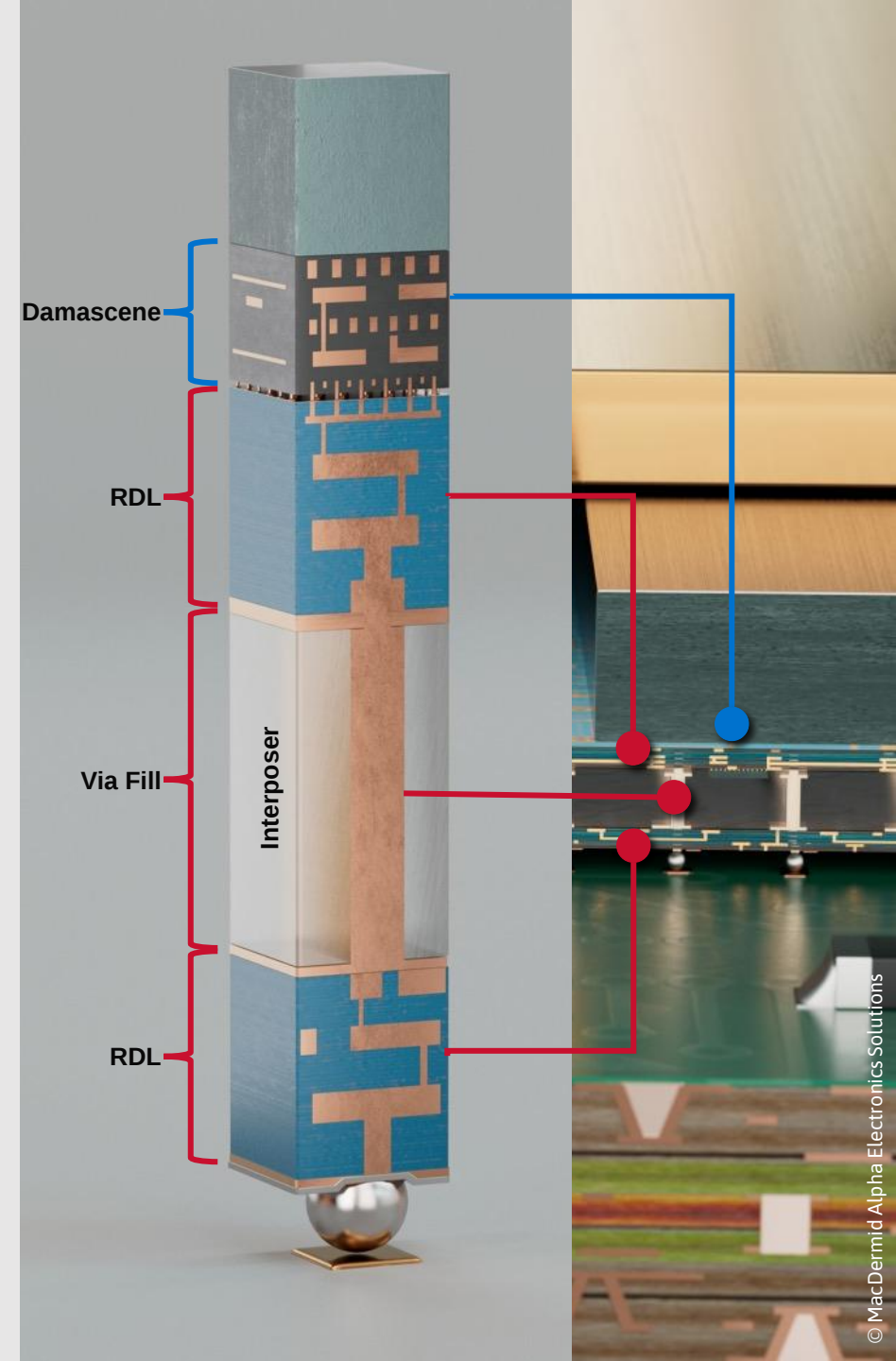
### ▪ Random-Distribution-Layer:

- **Where is it used?** Packaging-Level, Post-Wafer
- **Redirection** and **Rearrangement** of I/O contacts to connect Chip to package and substrate in  $\mu\text{m}$ -range



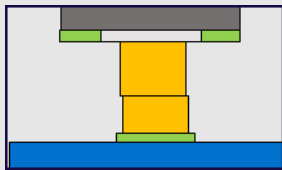
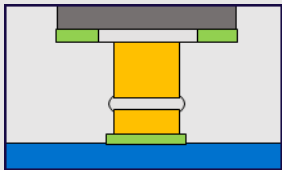
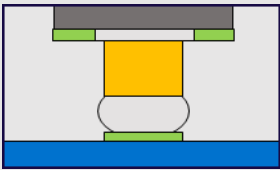
### ▪ Through-Silicon-Via:

- **Where is it used?** Packaging Level, Mid-End
- Used for **vertical Die-to-Die** Connections
- **Challenges, CTE-Mismatch** Cu to Interposer material, **Yield-improvement** by using robust galvanic chemicals and processes, **Costs**

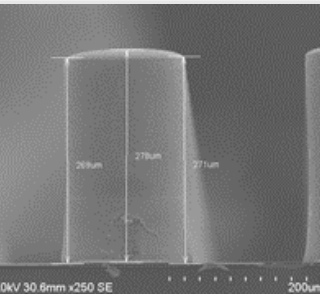
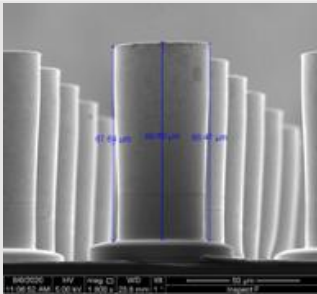
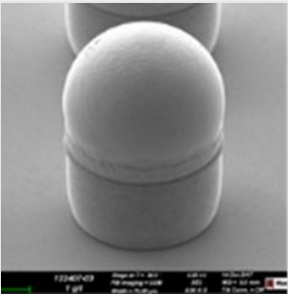


# Interconnect Technologies

## Bump, Micro-Bumps, Pillars



|                 |                          |                                       |                        |
|-----------------|--------------------------|---------------------------------------|------------------------|
| Bonding Method  | C2 FC with Cu Pillar     | Thermal compression FC with Cu Pillar | Thermal compression FC |
| Bump Pitch      | 140 ~ 60 $\mu\text{m}$   | 80 ~ 20 $\mu\text{m}$                 | <30 $\mu\text{m}$      |
| Bump Metallurgy | Cu + Solder (SnAg or Sn) | Cu + Solder (SnAg or Sn) Cap          | Cu                     |



Finer pitch, Current carrying, Thermal performance, Reliability, Signal integrity



# Interconnect Technologies

## Low-Alpha Tin

### ▪ Challenge and Development:

- High-density Packages can be sensitive to radiation exposure.
- Effects are Soft-Errors in Flip-Chip, SiP or Memory-Packages
- Low-Alpha Tin (Sn) can mitigate or eliminate this influence.
- Main source radioactive isotope Pb-210 with half-life-period of ~22years.
- Development of specific refining processes, controlled supply chain, material selection with aged tin, verification methods to test  $\alpha$ -emissions of the final product.
- Tin-variants
  - Standard Sn: 10-100  $\alpha/\text{cm}^2\cdot\text{h}$
  - Low-Alpha Sn: 0.002-0.02  $\alpha/\text{cm}^2\cdot\text{h}$
  - Ultra-Low-Alpha Sn: <0.001  $\alpha/\text{cm}^2\cdot\text{h}$

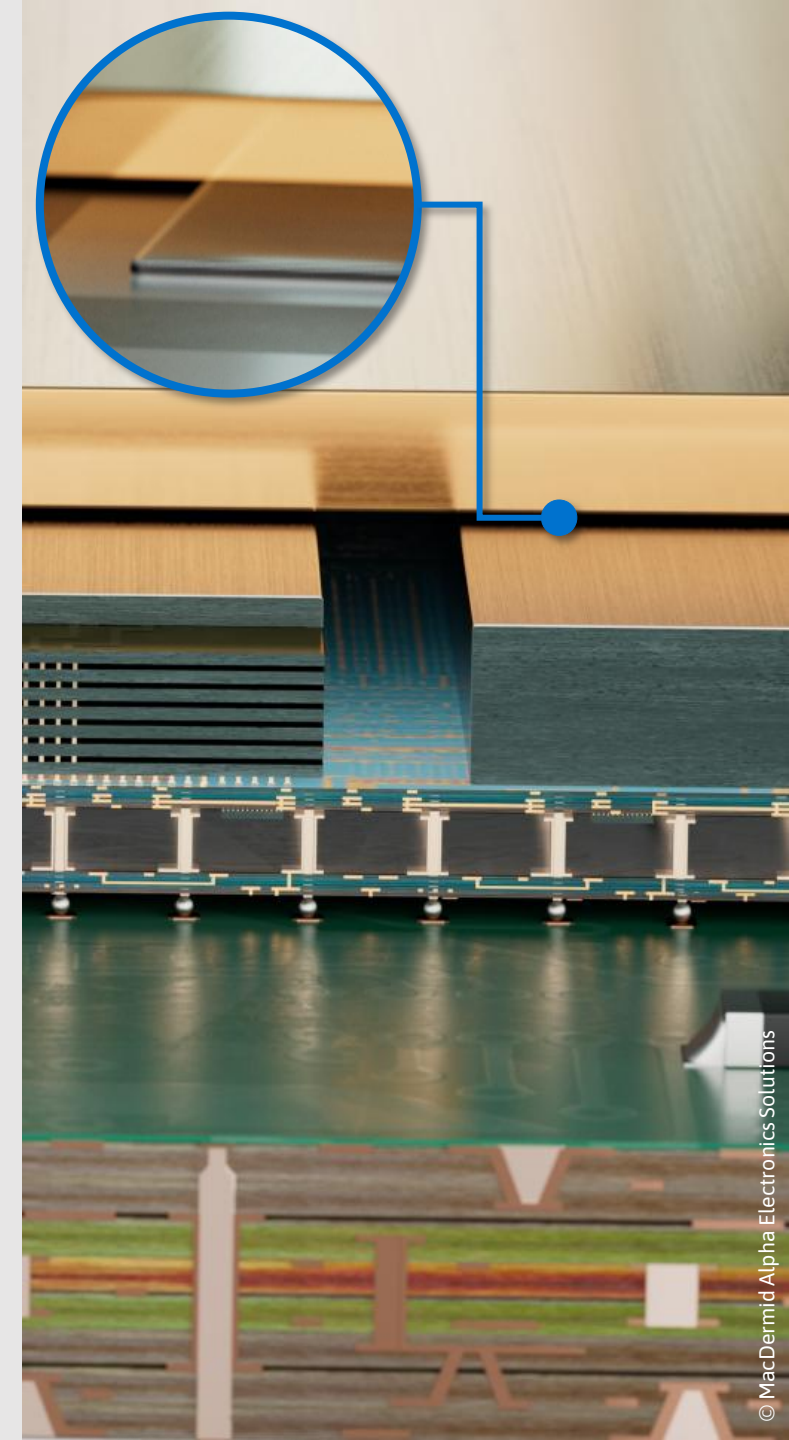
### ▪ Benefits:

- **Improvement of Signal-Integrity**
- **Increased Reliability** in HPC, Automotive Safety and Memory-Systems
- Fulfillment **JEDEC-requirements** e.g. JESD97A, JESD89A

# Thermal Solutions

## Enabling High Performance Applications

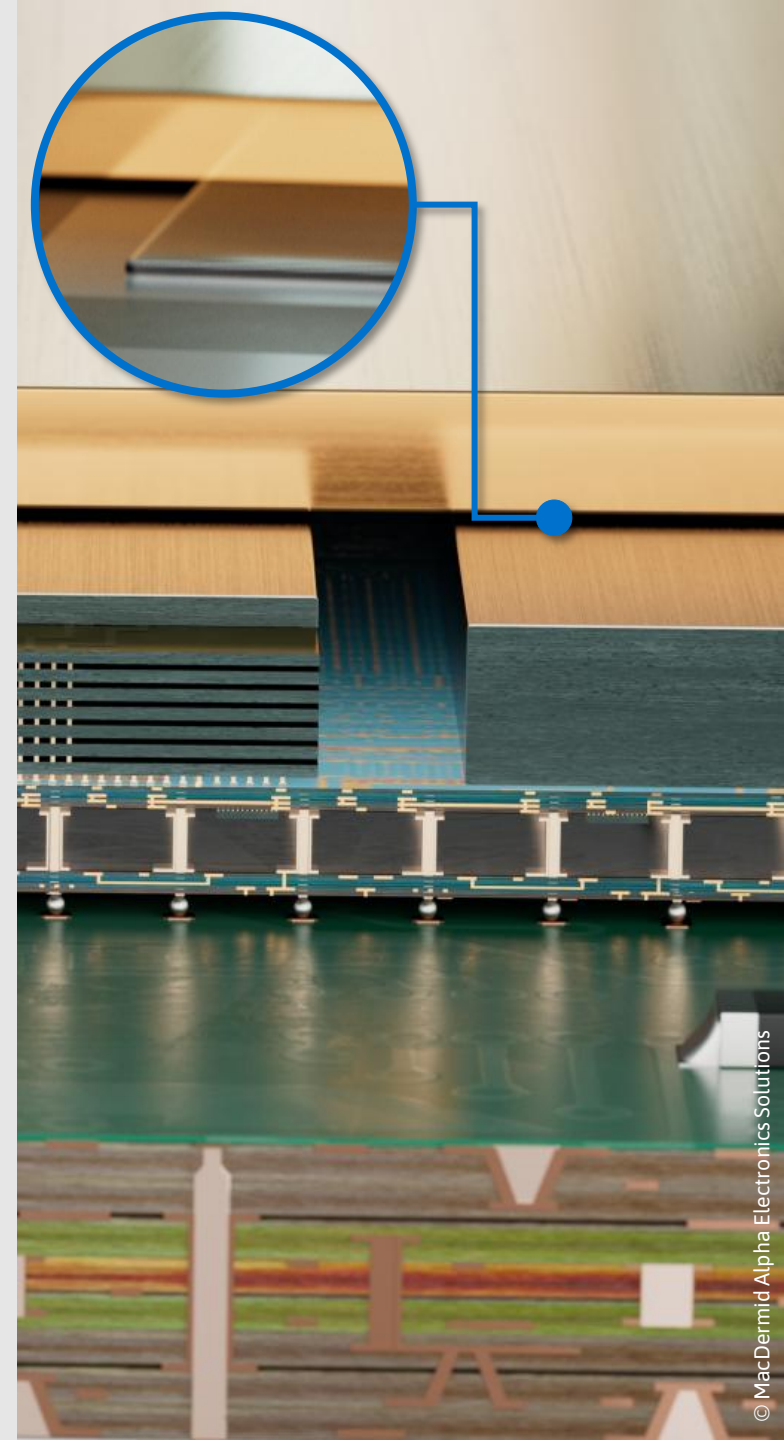
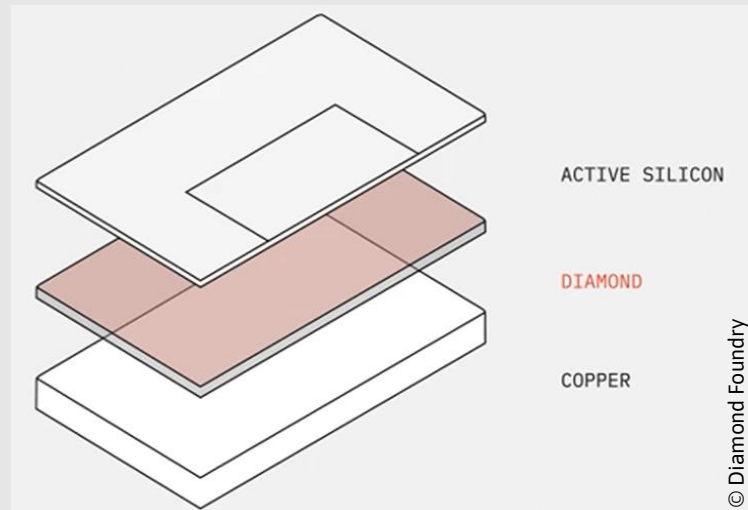
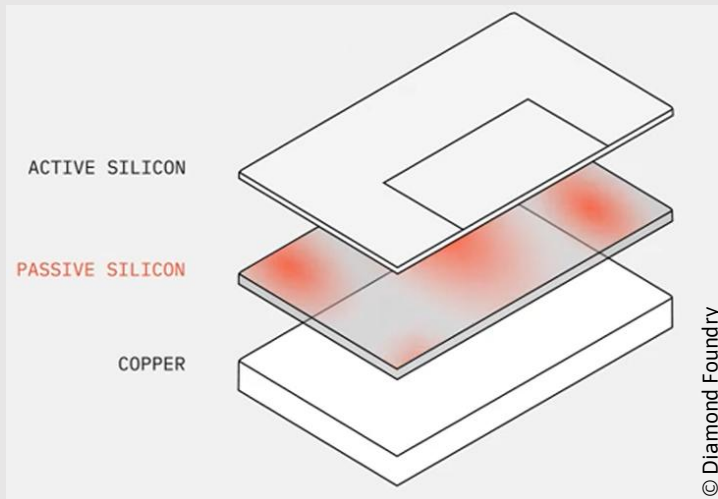
- **Power Density:**
  - **Increase** of functionality leads to higher heat output
  - **Modern HPC- or Ai-Packages** already reached **>1W/mm<sup>2</sup>**
  - **Uneven power output** reinforces **hotspot** effects
- **Reliability:**
  - Uneven **Hotspot distribution** creates temperature gradients within the packages
  - **Increase of Mechanical Stresses** and **Degradation** on the packages
- **Challenges and Trends:**
  - **Improvement** on **Rth-Path** for the complete package
  - **Reduction of Interfaces** or **Improvement** of their quality
  - Usage of **New Materials**, **Spreader** and **Cooling** solutions



# Thermal Solutions

## Enabling High Performance Applications

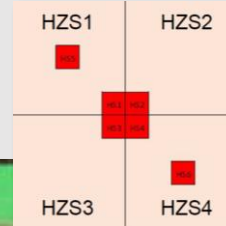
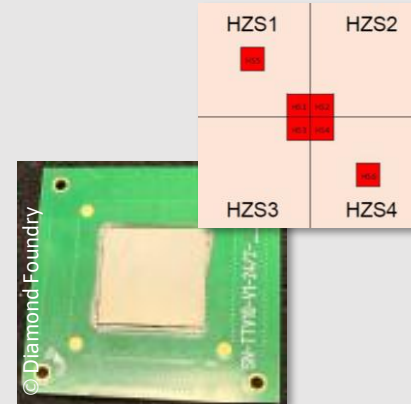
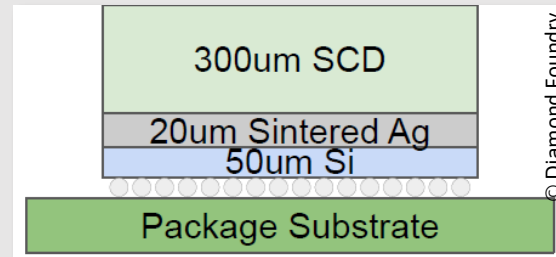
- **Reinventing, Re-Designing**, and using **New Materials** in this type of application
- Introduction of **Diamond Substrates** and **Silver Sintering** Technology
  - **Increase of Thermal Conductivities (X-Y-Z) of Spreader and Interconnection Material**
  - **CTE-Adjustment**



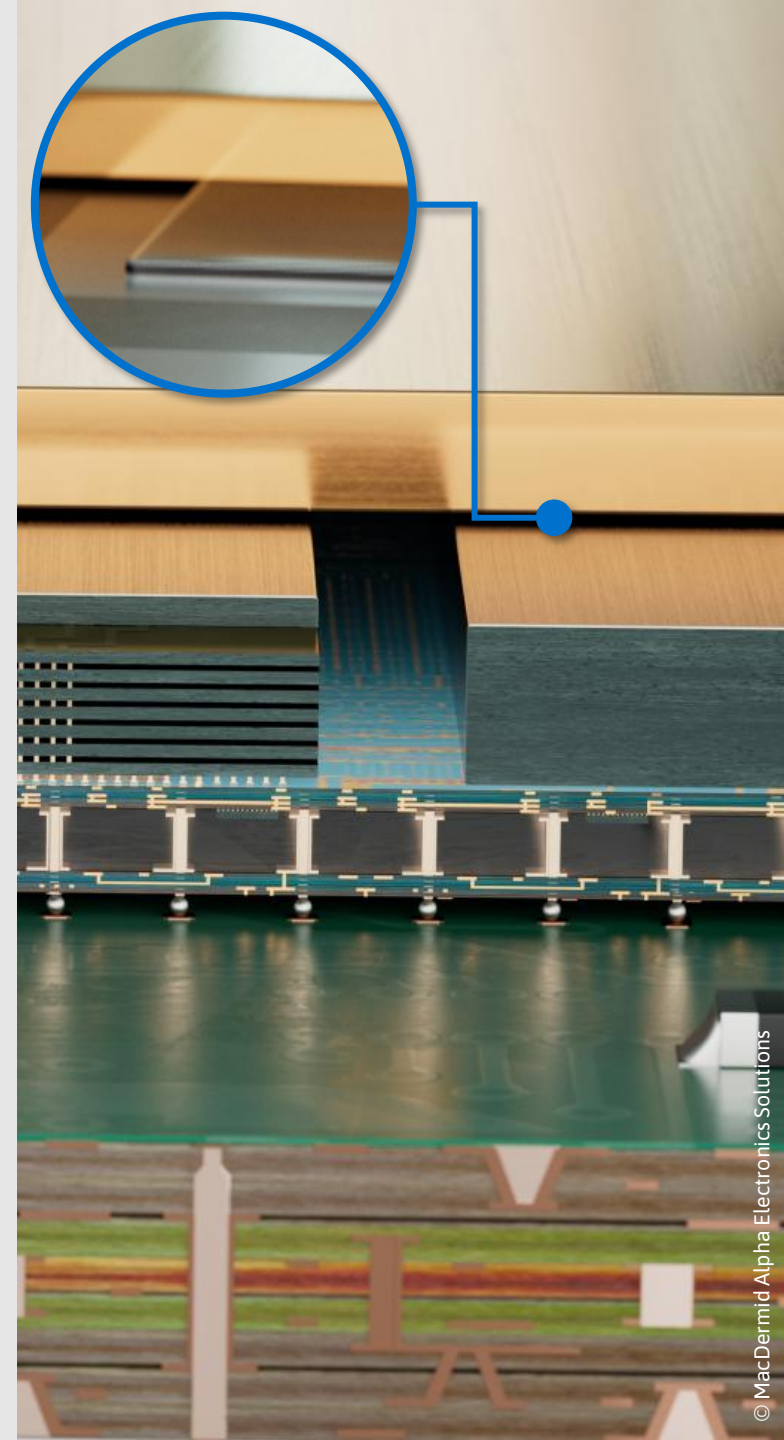
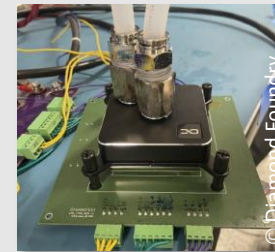
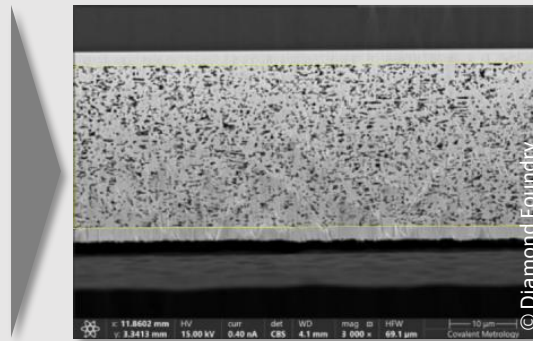
# Thermal Solutions

## Enabling High Performance Applications

### ■ Test Vehicle and Setup



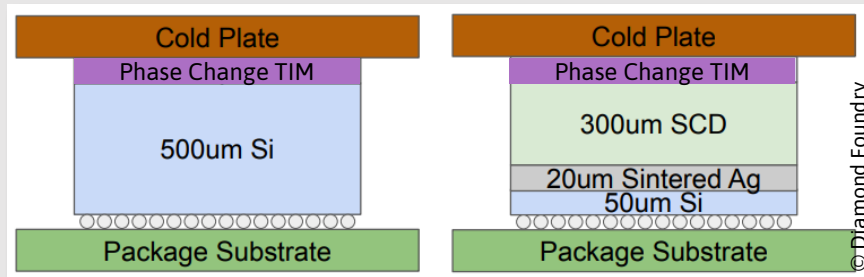
- **Low Sintering Pressure** through the use of **Nano-Scale-Particles**
- **Uniform and Co-Planar layer** through the use of **Films and Preforms**



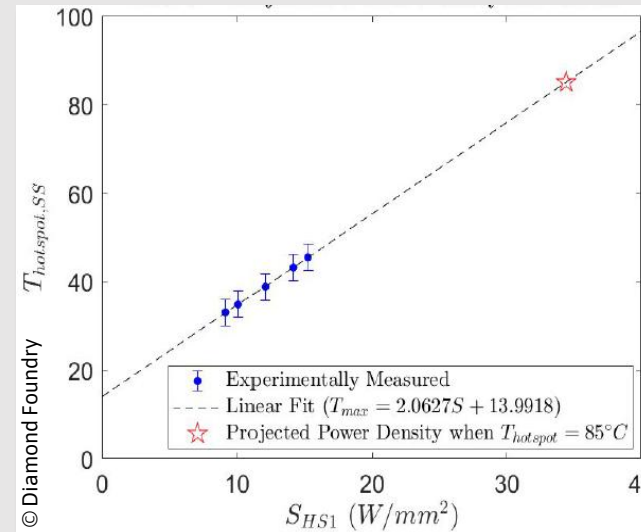
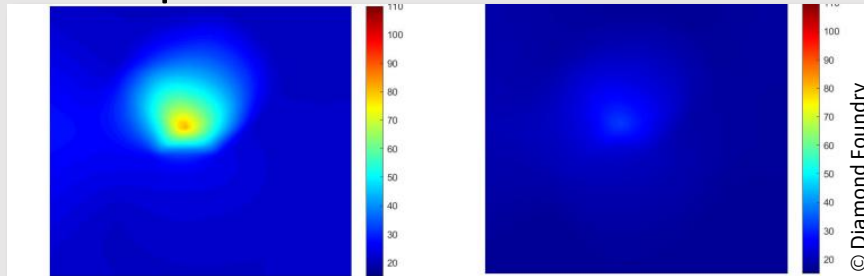
# Thermal Solutions

## Enabling High Performance Applications

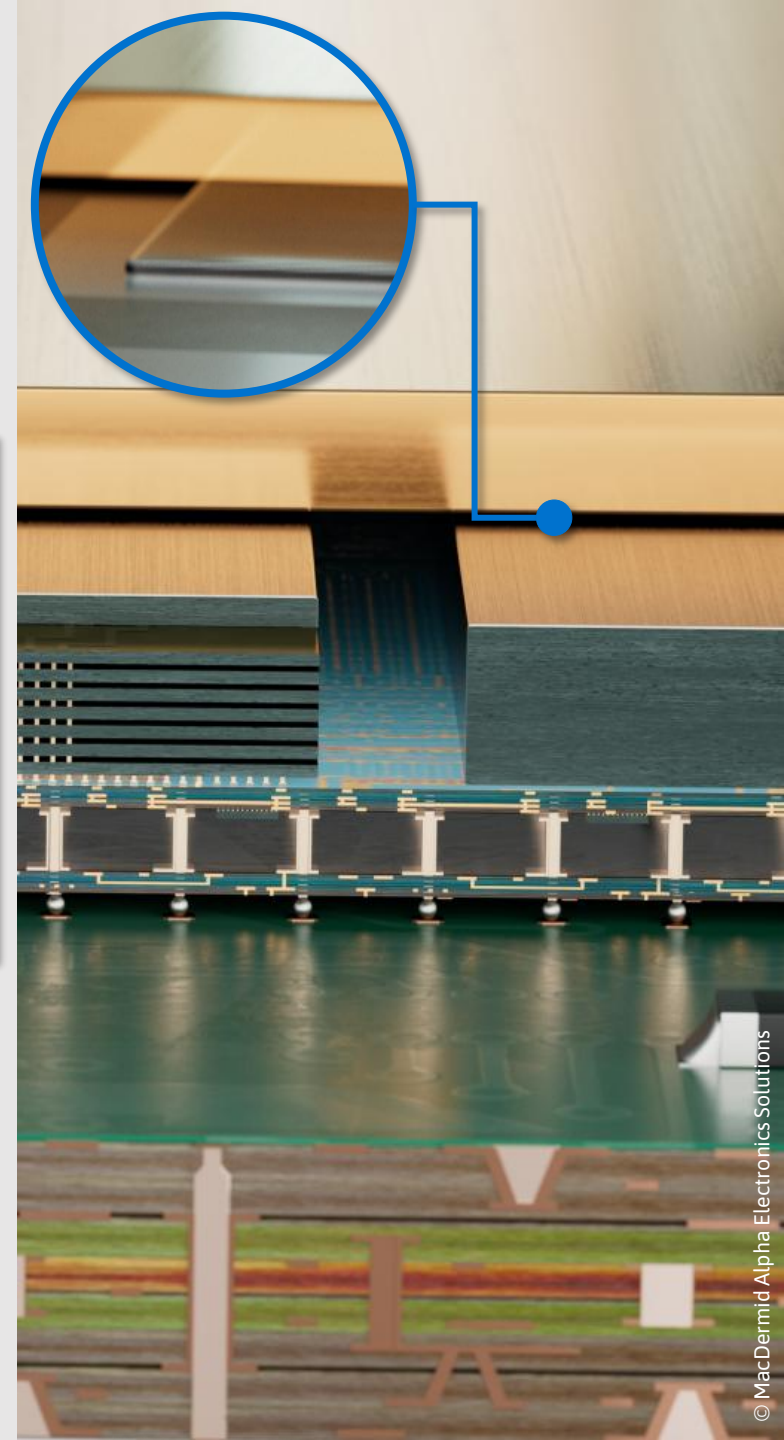
### Test Results



Experiment for 6.25mm<sup>2</sup> HS1



- **52K Reduction** at 9.2 W/mm<sup>2</sup>
- **Projected 3.8x Increase** in **Power Density @ 85°C**
- **Projected Power Density** at 85°C of **34.4 W/mm<sup>2</sup>**

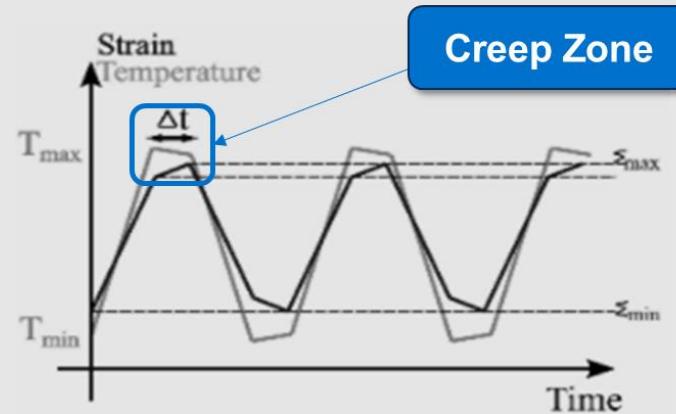
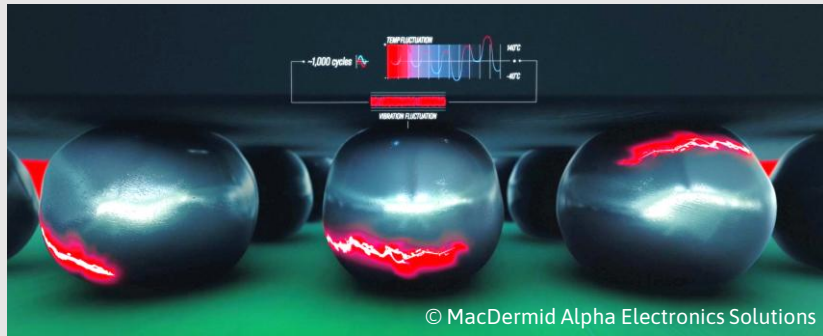


# Interconnection Material

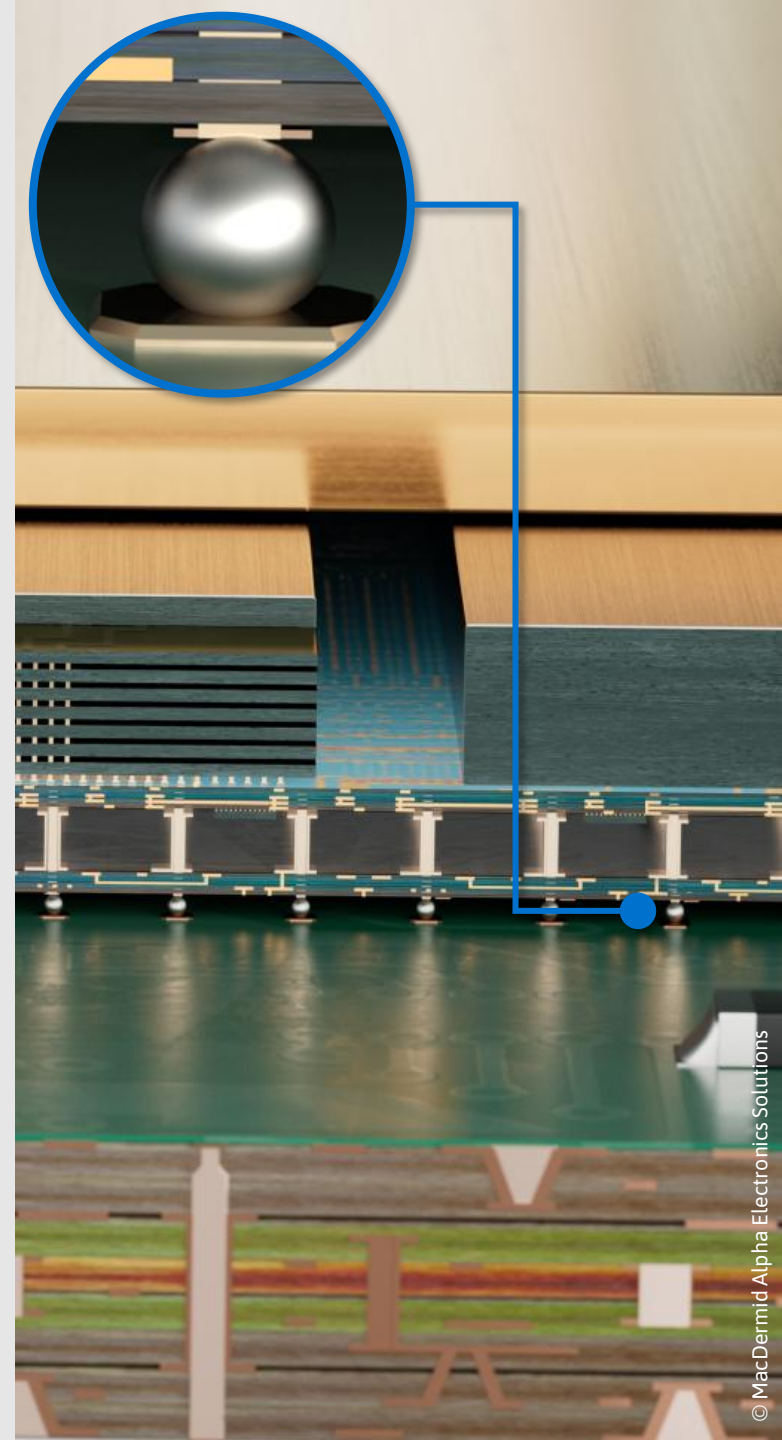
## Package Interaction with PCB Assembly

### ■ Challenges and Trends:

- The trend toward smaller structures, thinner packages, and higher I/O density is extending to other package forms e.g. BGAs.
- **Reduced stand-off heights** result in **increased** mechanical and thermal stress.



- **New alloys** are being developed to **better tolerate** the increased stresses.
- The focus is on modifying grain boundaries, diffusion behavior, and hardness characteristics.



# Closing

- Moore's Law has driven semiconductor innovation for more than five decades.
  - **Original formulation (1965): *The number of transistors on an integrated circuit doubles approximately every 12 to 24 months, while the cost per function remains constant.***
- Scaling is reaching its physical and economic limits.
- Transistor technologies are largely mature – further miniaturization requires extreme investment.
- Innovation now happens at the system level.
  - Advanced Packaging, Chiplets, 2.5D/3 Integration, and SiP.
  - Materials, interconnects, and thermal management are becoming decisive performance enablers.
- Industry must remain technology-open
  - to explore non-traditional approaches and unconventional material combinations.
  - fostering progress beyond classical scaling boundaries.
- Future progress = smarter, cross-disciplinary integration – not just smaller transistors.



**MacDermid Alpha**  
ELECTRONICS SOLUTIONS



# Contact us



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# Thank you for your attention!